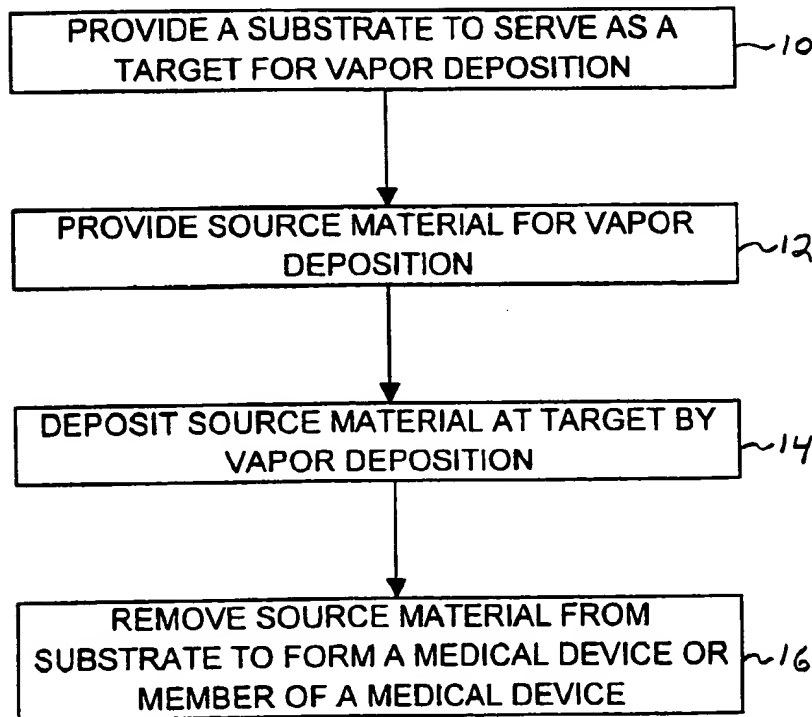




US 20030018381A1

(19) **United States**(12) **Patent Application Publication****Whitcher et al.**(10) **Pub. No.: US 2003/0018381 A1**(43) **Pub. Date:****Jan. 23, 2003**(54) **MANUFACTURING MEDICAL DEVICES BY
VAPOR DEPOSITION****Related U.S. Application Data**(63) Continuation of application No. 09/490,613, filed on
Jan. 25, 2000, now abandoned.(75) Inventors: **Forrest D. Whitcher**, Allston, MA
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(52) U.S. Cl. **623/1.15; 427/2.24**(57) **ABSTRACT**

A method of forming a medical device, the method including the steps of providing a substrate, depositing a metallic layer on the substrate by a vapor deposition process, and removing the metallic layer from the substrate. The metallic layer thus removed is the medical device or serves as a basis for forming the medical device. In another aspect, the present invention includes a medical device formed by the process of the present invention.

(73) Assignee: **SCIMED LIFE SYSTEMS, INC.**(21) Appl. No.: **10/242,382**(22) Filed: **Sep. 12, 2002**

*ion beam sputter etc
vacuum
rate > .05 mm/min
rotate substrate*

*control heterogeneity
material
55.9 M²*